

# CMOS and Timing (LFoundry LF15A, 150 nm)



irfu



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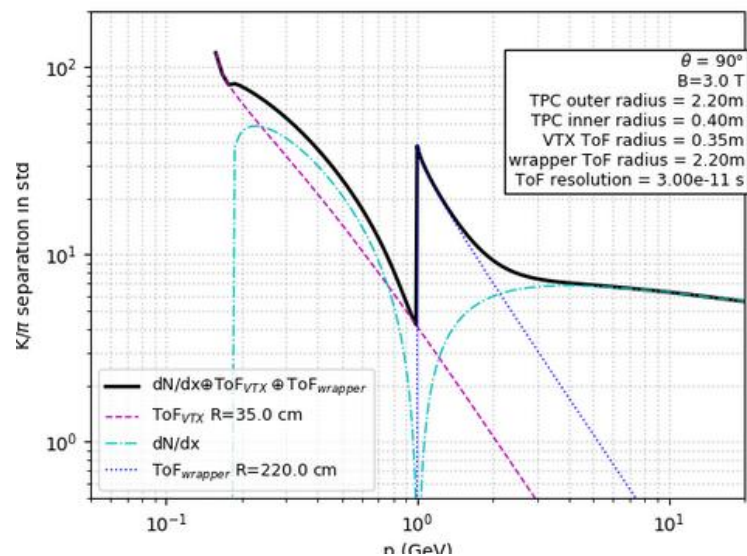
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# Motivations for a TOF detector



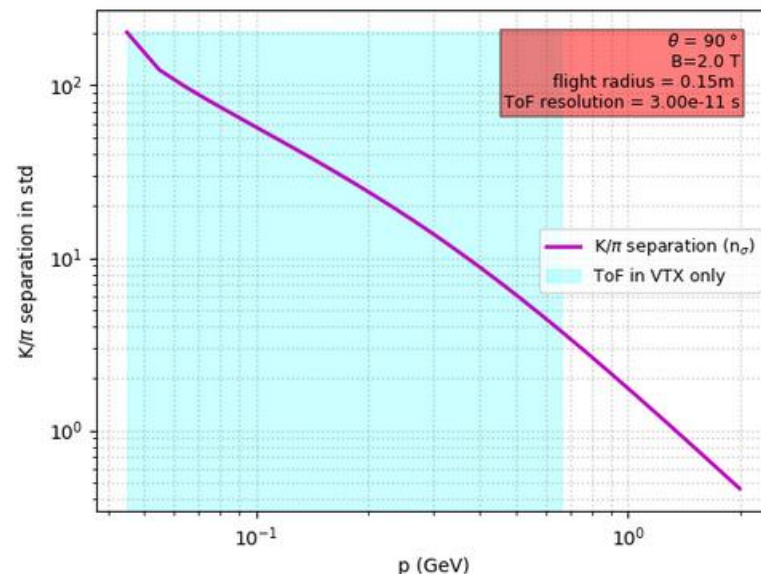
Improve  $\pi/K$  separation at low momentum  
 TOF wrapper radius 2.2 m

Physics cases :

$H \rightarrow \text{fermions}$

Flavour physics

Heavy Neutral Leptons



TOF wrapper could be complemented  
 by timing layer (radius 15 cm) for  
 $0.045 < p < 0.66 \text{ GeV}/c$  (not reaching the 2.2 m wrapper)

Expression of Interest

Toward MCMOS Time of Flight Tracking

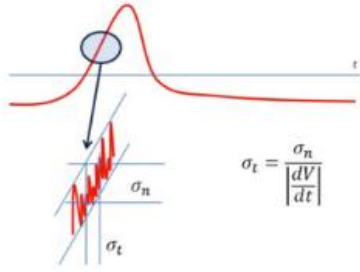
Layers for a detector at FCC-ee, IP2I and Ifu

# Features of monolithic CMOS sensors

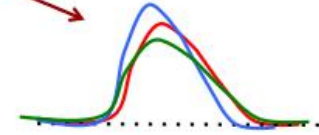
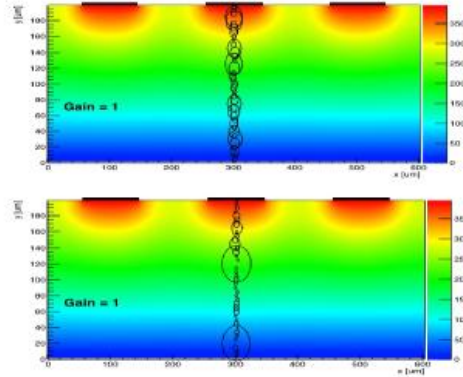
- (Relatively) cheap high volume industrial technology
  - 2-3 k euro/8" wafer, post-processing and dicing included → bare sensor cost for 100 m<sup>2</sup> : 7-11 M euros
  - Bump bonding operation not needed for fully monolithic architecture
- Stable and easy operation
- HV-HR wafers available, allows charge collection by drift and not only by diffusion → favorable for fast collection and also for radiation hardness
- Can be designed as a complete SoC, from sensor to DAQ interface
- Presently available technologies are known to be rad-hard up to a few 10<sup>15</sup> 1 MeV neq/cm
- Can be thinned down to < 100 μ

# Time resolution ingredients

$$\sigma_t^2 = \left( \frac{\text{Noise}}{dV/dt} \right)^2 + (\Delta \text{ionization})^2 + (\Delta \text{shape})^2$$



"Jitter" term



Signal shape is determined by

Ramo's Theorem

$$i \propto qvE_w$$

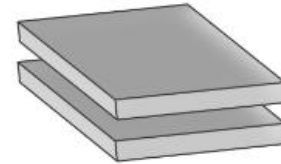


Illustration taken  
From N. Cartiglia  
(VCI 2022)

Small noise  $\rightarrow$  choice of  
technology, small detector  
capacitance

High  $dv/dt \rightarrow$

High electric field (but  $V_d$   
saturates around 1 V/ $\mu\text{m}$ )

Intrinsic amplification ?

Amplitude variation  $\rightarrow$  Timewalk,  
corrected offline

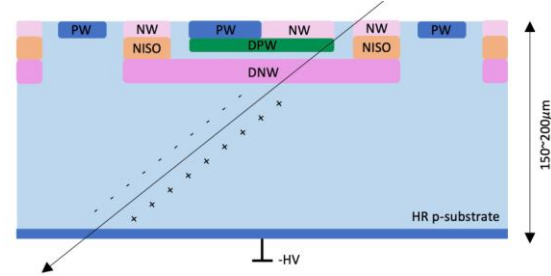
Non-homogeneous energy  
deposition  $\rightarrow$  cannot be corrected,  
minimized by design (thin sensor)

Saturated drift velocity  
in sensor volume  $\rightarrow$   
Uniform weighting field

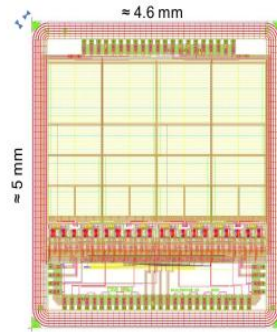
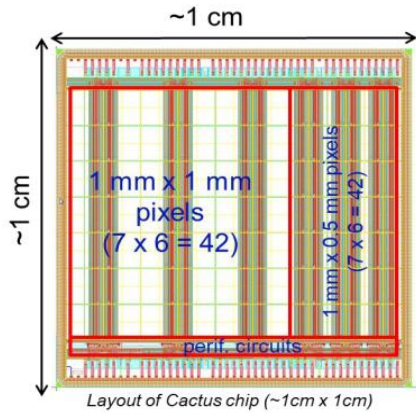
Parallel plate geometry,  
easier for big pixels  $\rightarrow$   
Large electrode designs

# CACTUS sensor development line

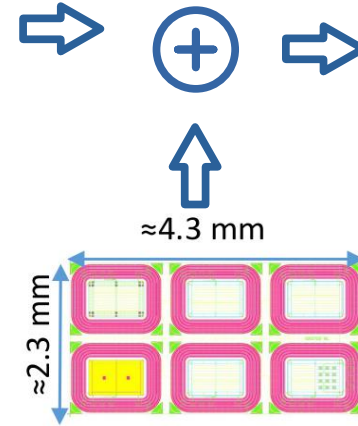
- Monolithic timing using Lfoundry 150nm HV-CMOS
- Large fill factor



Cross section of the MiniCACTUS\_v2



MiniCACTUS\_v2 2023  
 -coupling problems solved  
 -new front-ends  
 -49 ps time resolution



MiniCACTUS\_v2  
 with gain  
 2025?

CACTUS Demonstrator 2017

- 500 ps resolution only (parasitic caps)
- high BV (>250 V)
- Good yield
- Good charge collection uniformity

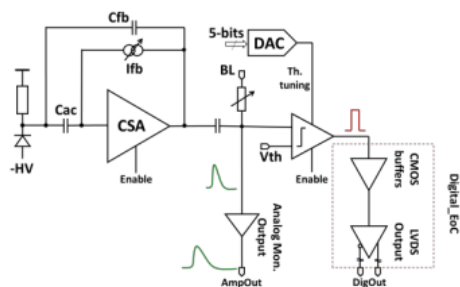
MiniCACTUS\_v1, 2020

- 65 ps time resolution
- Some digital/analog couplings

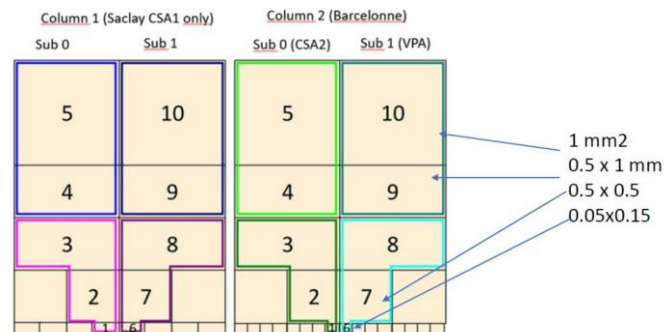
CACTUS-GL 2024

# MiniCACTUS\_v2

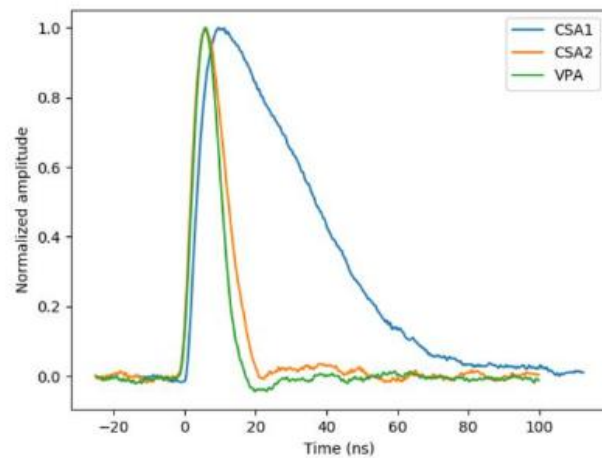
- Slow control, DACs and bias on-chip
- Pixel sizes:  $1 \times 1 \text{ mm}^2$ ,  $1 \times 0.5 \text{ mm}^2$ ,  $0.5 \times 0.5 \text{ mm}^2$
- Post-processed samples to 150, 175 and  $200 \text{ }\mu\text{m}$
- CEA-IRFU and IFAE collaboration
- No gain on sensor
- Featuring three pre-amplifiers:
  - Two CSA and one VPA
  - Different return-to-baseline times ( $< 25 \text{ ns}$  for CSA2 and VPA)



## Sensor FE architecture



## Pixels overview

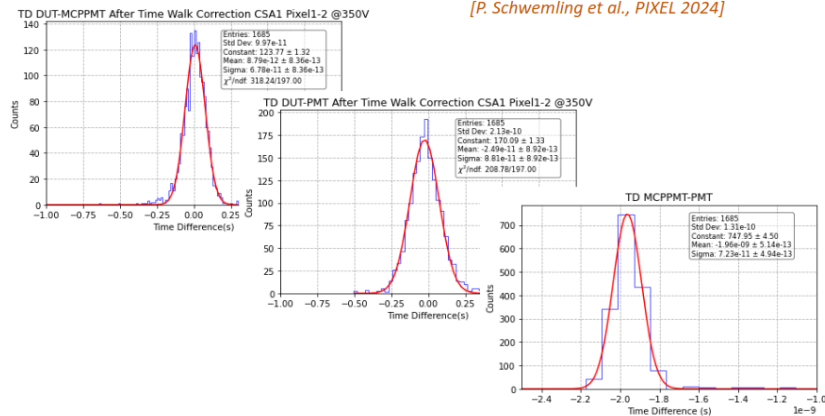
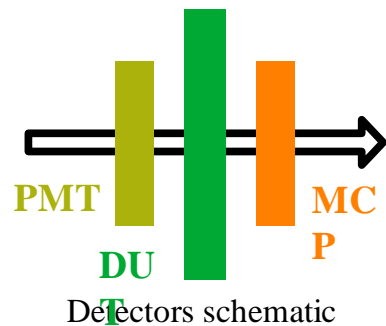


Return-to-baseline time

- Three testbeam campaigns at CERN SPS:
  - July 2024 (parasitic DRD1, muons)
  - July 2025 (parasitic DRD1, muons + pions)
  - October 2025 (DRD3, pions)

# Testbeam July 2024

- First TB studying MiniCACTUS\_v2
- 12 bit, 10 GS/s, 1 GHz bandwidth scope
- Issue with DUTs getting shorted on the sensor HV, causes understood later
- CERN SPS/H4 North Area with muons
- Best result of  $\sim 60$  ps on  $0.5 \times 0.5$  mm<sup>2</sup> pixel with 175  $\mu$ m thickness @ 350V

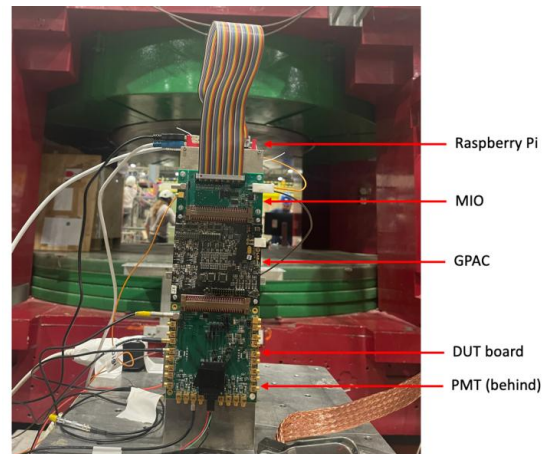


5	10	5	10
4	9	4	9
3	8	3	8
2	7	2	7

**Sigma (DUT)**  
59.9 ps

**Sigma (PMT)**  
64.4 ps

**Sigma (MCP)**  
32.5 ps



DUT setup

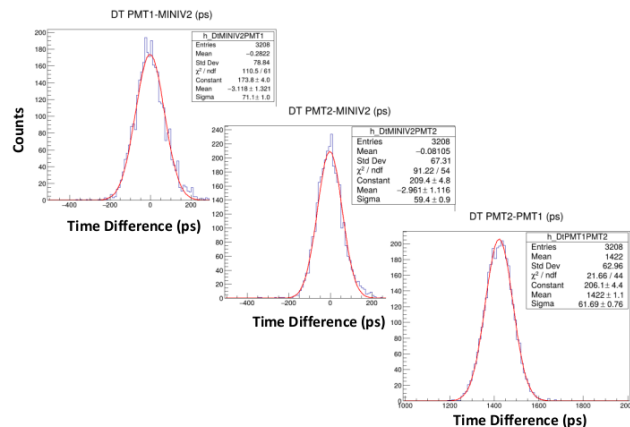


# Testbeam July 2025

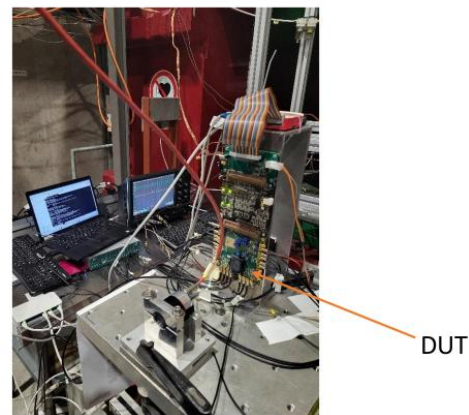
- 12 bit, 10 GS/s, 1 GHz bandwidth scope
- HV issue solved:
  - Increased HV lines isolation on PCB
  - Reducing amount of HV wire bonds over guard-rings
- CERN SPS/H4 North Area with muons and pions
- Best result of  $\sim 49$  ps on  $0.5 \times 0.5$  mm<sup>2</sup> pixel with 175  $\mu$ m thickness @ 500V



Detectors schematic



Sigma (DUT)	Sigma (PMT)	Sigma (MCP)
48.88 ps	51.64 ps	33.76 ps

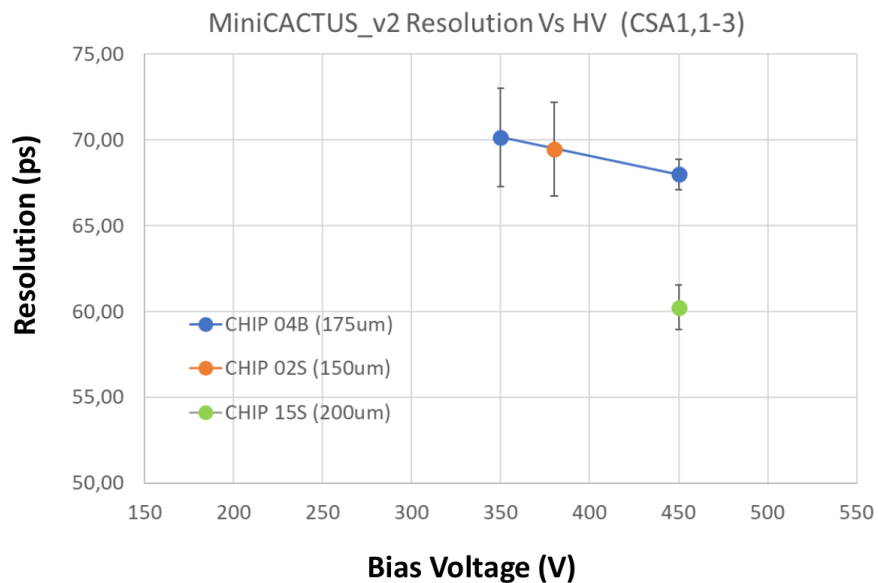


DUT setup

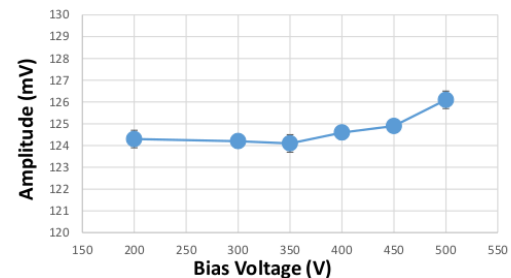


# July 2025 – Timing on 1x0.5 mm<sup>2</sup> pixel

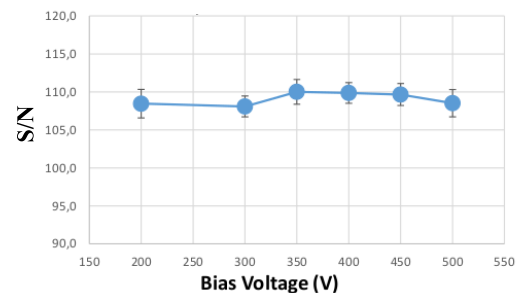
- Time resolution between 60 and 70 ps



Sensor output amplitude MPV vs HV

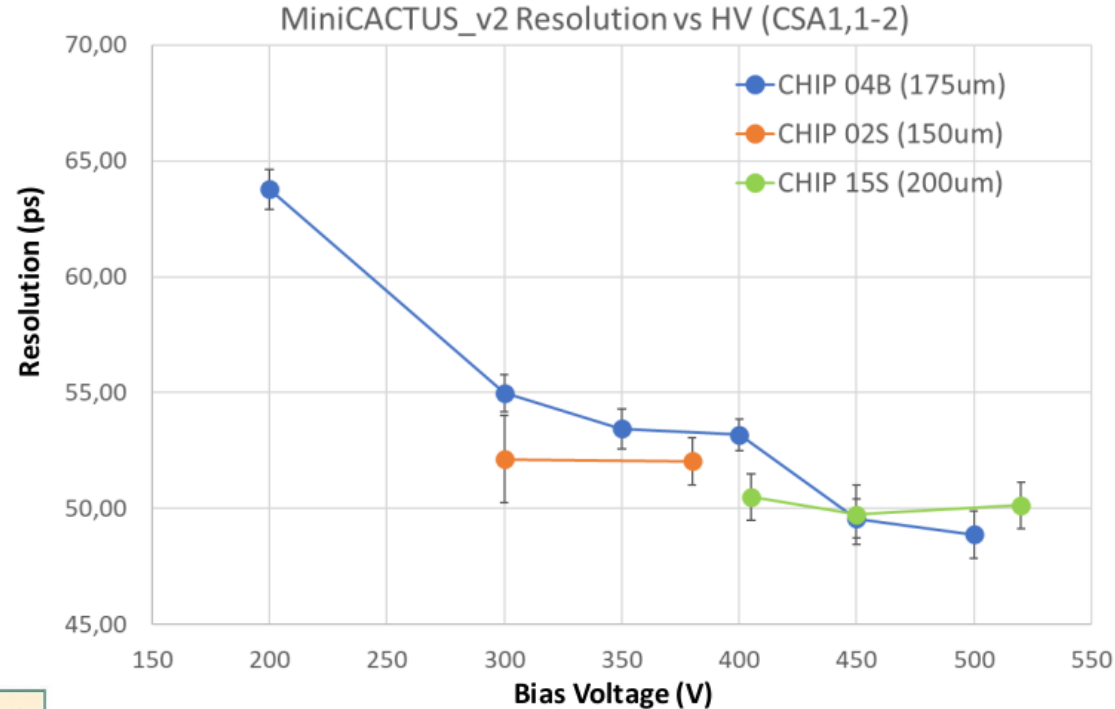


Sensor output Signal to Noise vs HV



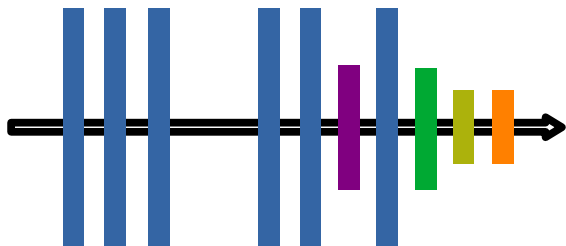
# July 2025 – Timing on 0.5x0.5 mm<sup>2</sup> pixel

- Time resolution better than 55 ps above 300 V, down to 48.9 ps at 500 V



# Testbeam October 2025 - DRD3

- 12 bit, 50 GS/s, 5 GHz bandwidth scope
- Using EUDAQ framework
  - Adapted producer from HGTD for the scope
  - Allowing to run Corryvreckan
- CERN SPS/H6 North Area with pions
- Detectors setup:
  - **EUDET Telescope**: tracking
  - **CROC**: For triggering ROI
  - **DUT**: MiniCactus\_v2
  - **PMT**: Auxiliar timing reference
  - **MCP**: Timing reference



Detectors schematic



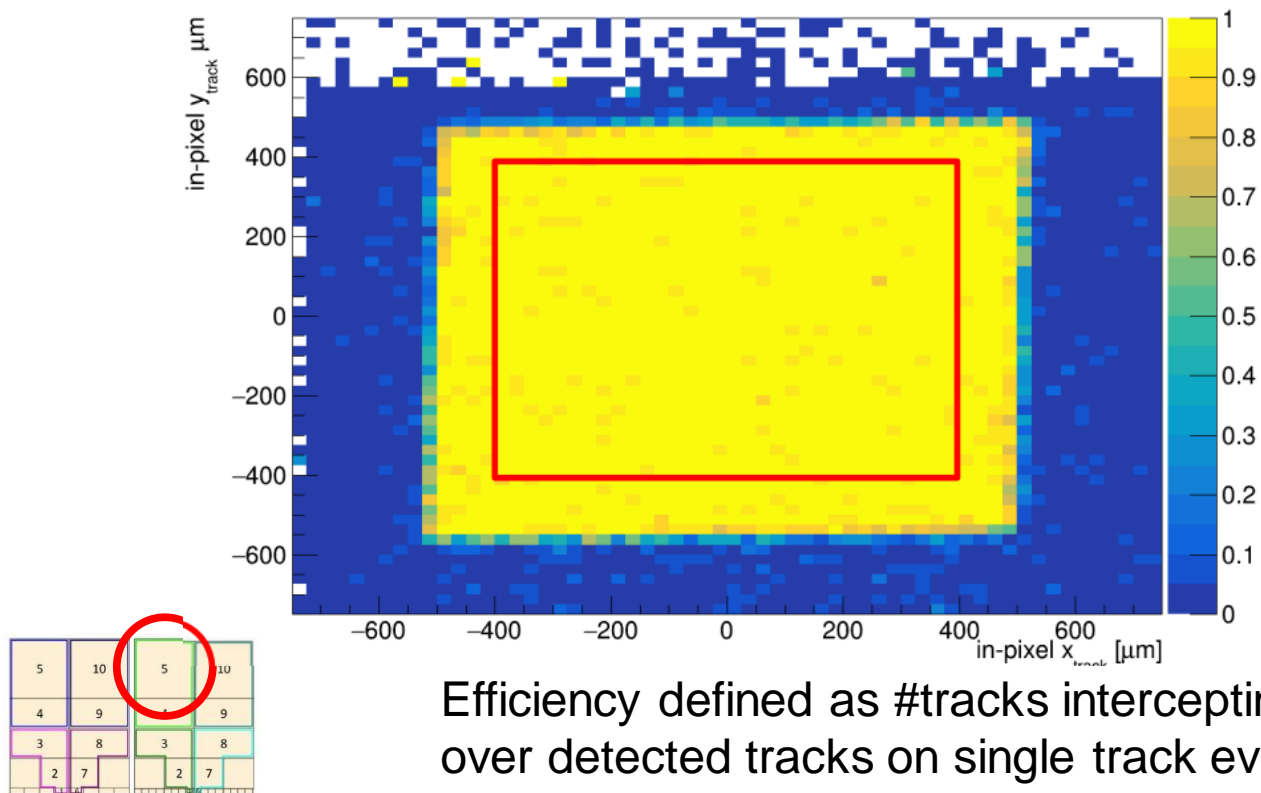
Zoom on DUT setup



DUT setup

# October 2025 – Tracking efficiency 1x1 mm<sup>2</sup>

- Tracking efficiency of  $99.0 \pm 0.1$  % on the central part on the pixel (in red, 0.8 x 0.8 mm) @350 V and 17 nA

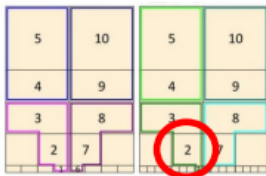
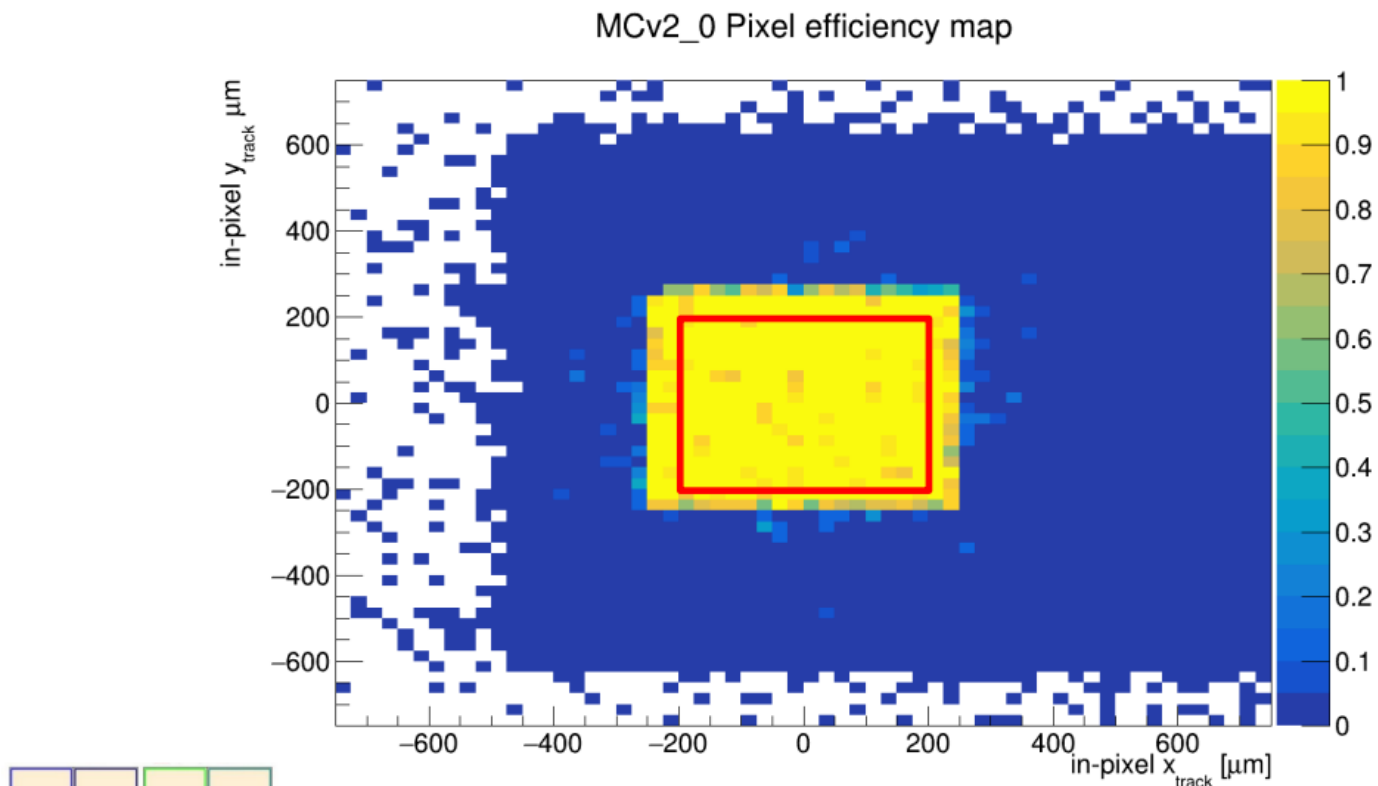


Efficiency defined as #tracks intercepting detector over detected tracks on single track events

*Preliminary – Ongoing analysis*

# October 2025 – Tracking efficiency $0.5 \times 0.5 \text{ mm}^2$

Tracking efficiency of  $98.6 \pm 0.3 \%$  on the central part on the pixel (in red,  $0.4 \times 0.4 \text{ mm}^2$ ) @400 V

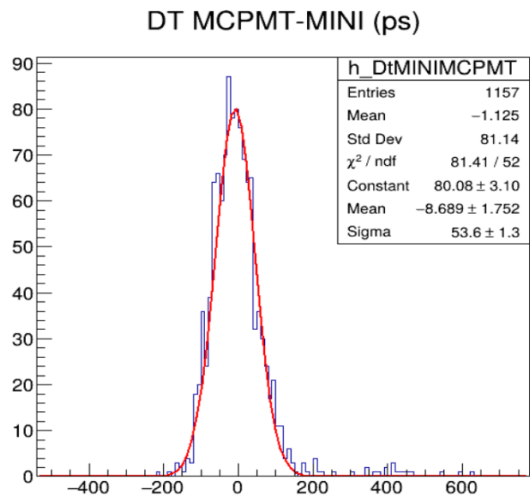


Efficiency calculated by tracks intercepting our detector  
over detected tracks on single track events

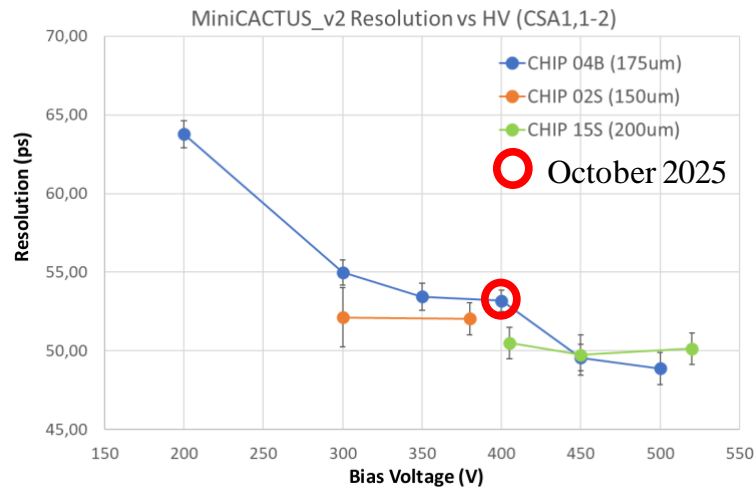
*Preliminary – Ongoing analysis*

# October 2025 – Timing results

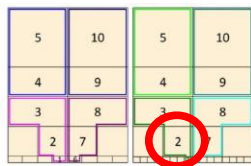
- Result of  $\sim 53.6$  ps on  $0.5 \times 0.5$  mm<sup>2</sup> pixel with 175  $\mu$ m thickness @ 400V
- Compatible with previously (July 2025) obtained resolution on CSA 1 of 54 ps:



CSA2  $0.5 \times 0.5$  mm<sup>2</sup> @400V



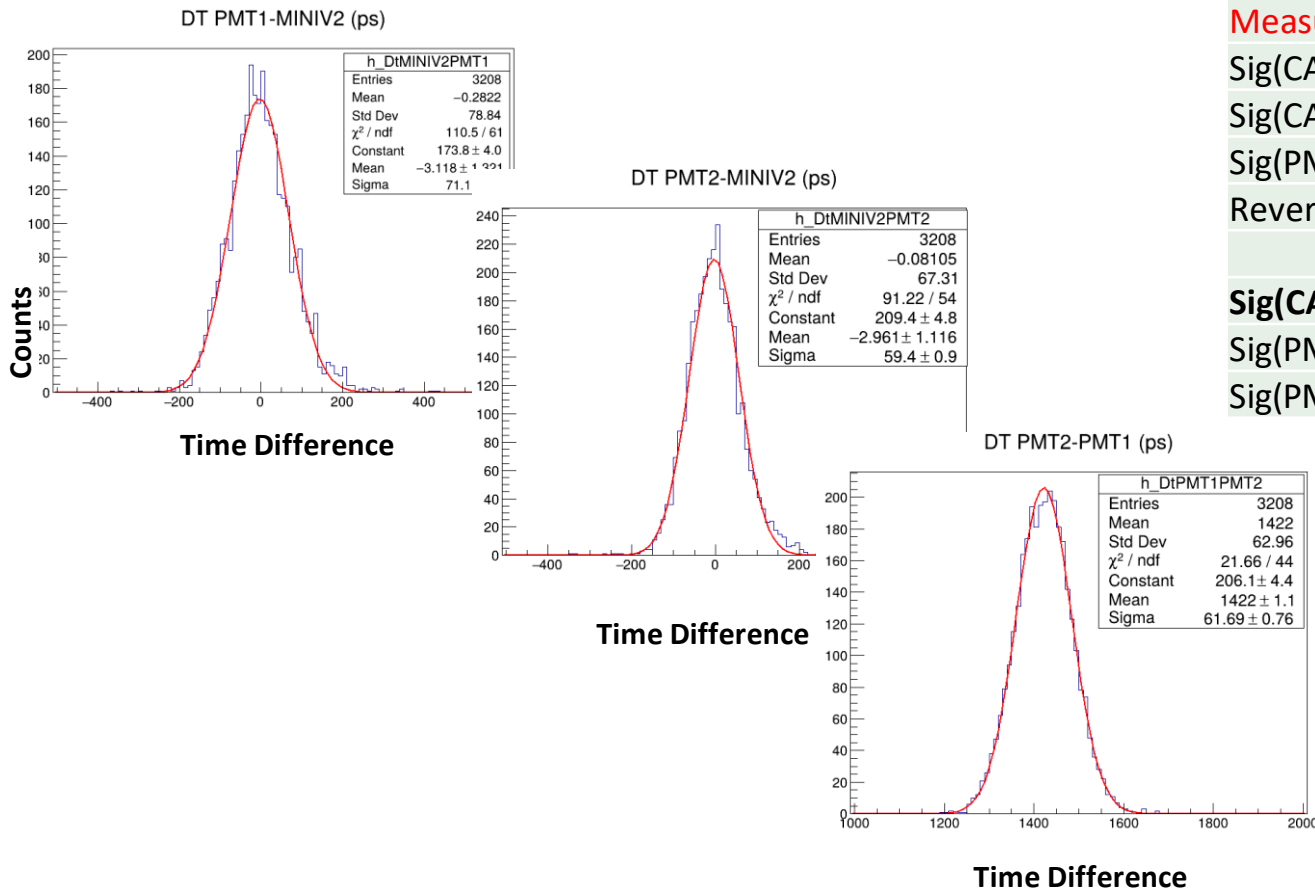
July 2025 Summary plot on  $0.5 \times 0.5$  mm<sup>2</sup>



*Preliminary – Ongoing analysis*

# Test-beam of MiniCACTUS\_v2 in July 2025

Chip#04B, pixel 1-2,  $0.5 \times 0.5 \text{ mm}^2$ ,  $175 \text{ }\mu\text{m}$ , -500V (Back-side pol.)



Measured Sigma Matrix after TW correction (ps)

Sig(CACTUS-PMT1)	71.1	1
Sig(CACTUS-PMT2)	59.4	0.9
Sig(PMT2-PMT1)	61.69	0.76
Reverse of the matrix to get the sigma of each devices		
	Resolution (ps)	Errors (ps)
<b>Sig(CACTUS)</b>	<b>48.88</b>	1.03
Sig(PMT1)	51.64	0.97
Sig(PMT2)	33.76	1.49

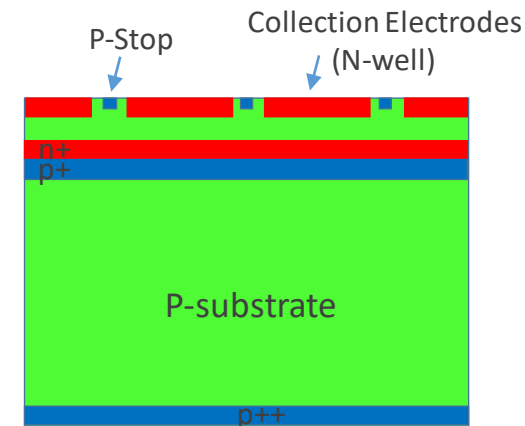
Power consumption in this configuration :  $0.6 \text{ W/cm}^2$



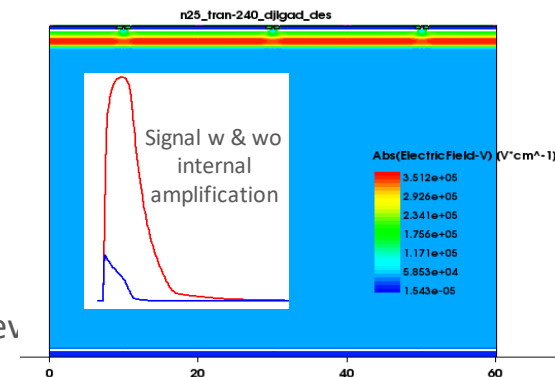
# How to improve further the performances: CACTUS-GL

- Add intrinsic gain to:
  - Improve S/N  $\rightarrow$  Potential improvement on time resolution
  - Reduce sensor thickness  $\rightarrow$  Reduce Landau fluctuations
  - Reduce FE power consumption
  - Reduce pixel pitch
- Ultimate goal is to reach <50 ps resolution
- CACTUS-GL prototype submitted to fabrication in May 2024 (MPW run)
  - Deep junction LGAD concept with buried PN-junction
  - Better radiation hardness expected with this concept
  - TCAD simulations done with Sentaurus
  - Charge multiplication factor of  $\sim 10$  expected from these simulations
  - PN junction implemented by the foundry (2 different P-dose versions)
  - Production implied only minimal modifications to LF15A standard process
    - change of implant energy of 1 layer (DNW)
    - addition of 1 customer layer
  - 6 diode structures with different guard-rings , 1 without gain layer
  - 2 epi (28  $\mu\text{m}$ ) and 2 HR wafers asked, HR wafers thinned & post processed similar to prev MiniCACTUS prototypes with 150  $\mu\text{m}$  thickness

Cross section of the active area of CACTUS-GL (not to scale)

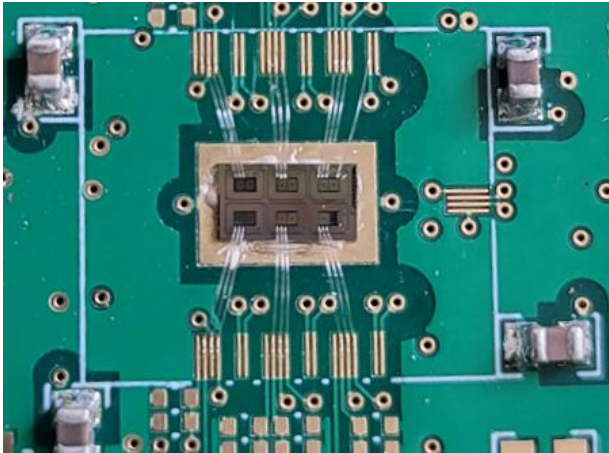


Typical Sentaurus TCAD simulation of a diode with buried PN junction

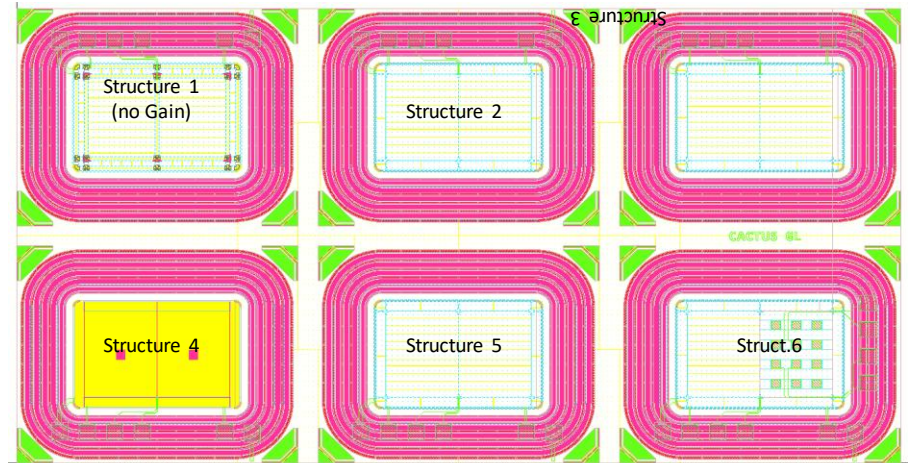


# Chip layout

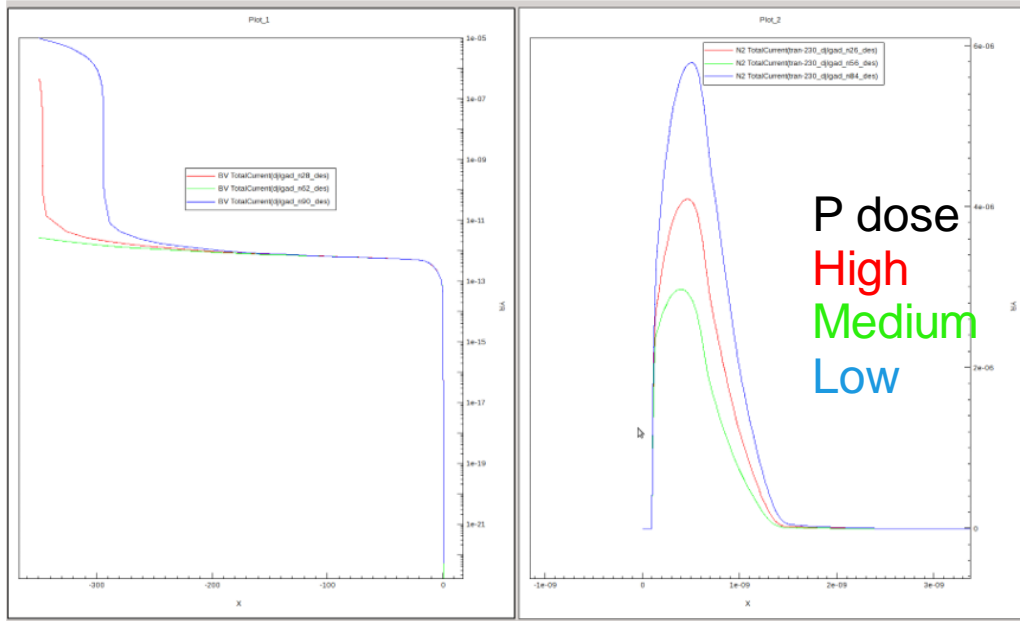
- 6 different diode layouts
- Each diode is split in two,
- and each half can be read out independantly
- One diode (structure 1) has no gain
- layer, for reference measurements
- Main difference from structure to structure
- is the guard rings



Layout of CACTUS-GL chip (2.3 mm x 4.3 mm)

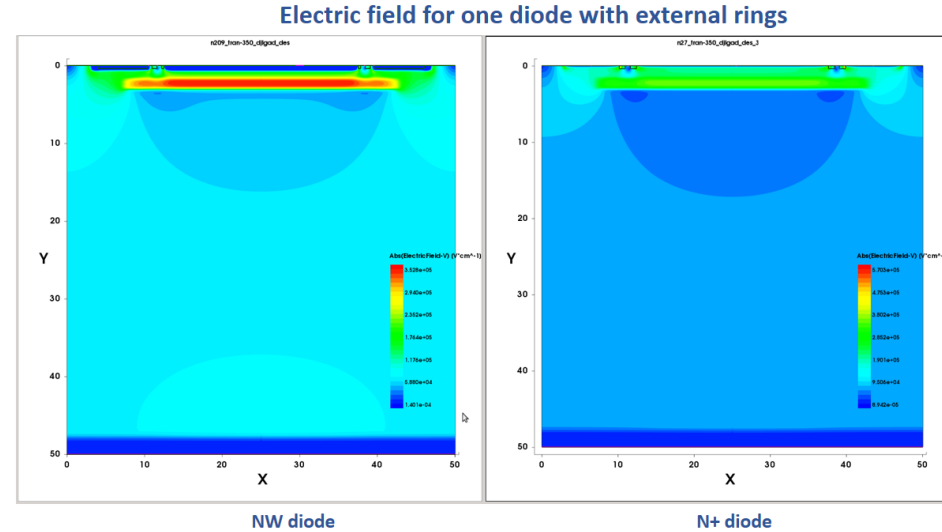


# TCAD simulation of MiniCactus-GL



I-V curves

Transient signal



NW diode

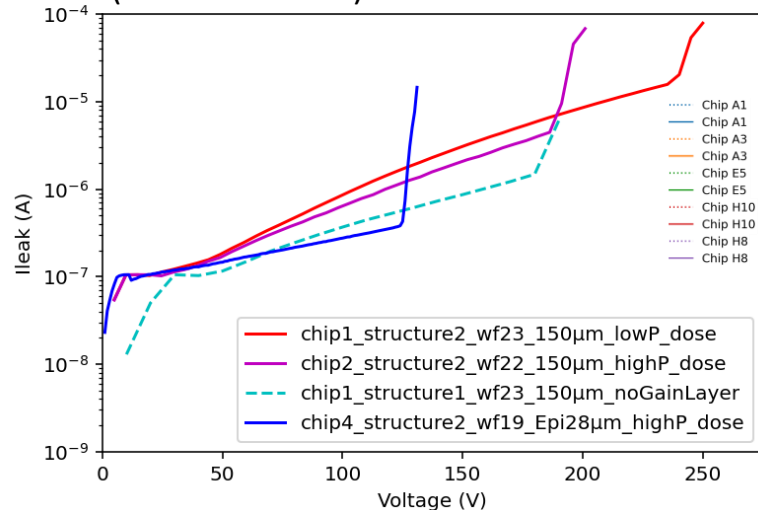
N+ diode

- Charge multiplication factor of about 10 looks possible
- Strong dependance of charge multiplication factor to P dose of gain layer structure → asked
- LF to produce wafers with two different P-dose settings
- Four wafers produced :
  - Two HR (two P-doses), thinned to 150  $\mu$ , post-processed at IBS (backside boron implant, metallization)
  - Two epi (two P-doses). 28  $\mu$ . diced at ALTER UK

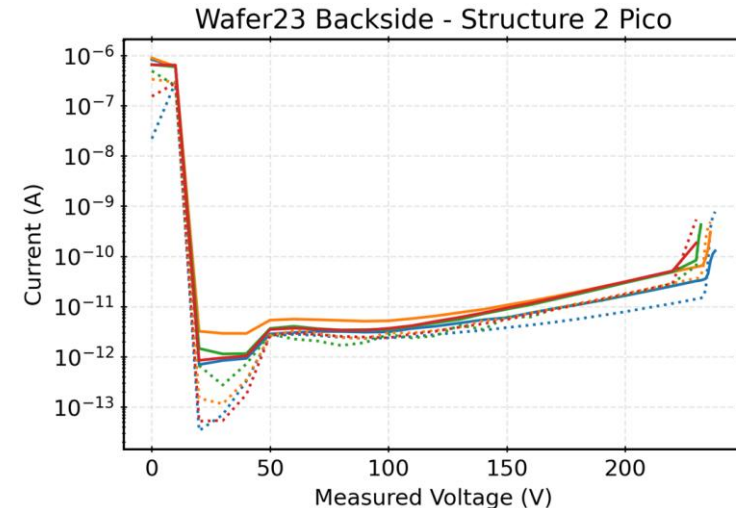
# Test Results from MiniCACTUS-GL : IV curves

- Fabricated and post-processed sensors received at the beginning of 2025
- Preliminary I-V measurements done at **Liverpool** using a probe-station and later at IRFU on sensors bonded on PCB.
- Conclusions :
  - All N-well diodes with gain layer have similar behavior. **Reproducible** curves from one chip to others
  - Difference on current measurements at low bias between probe station and PCB induced by test setup (intercurrent between two half diodes)

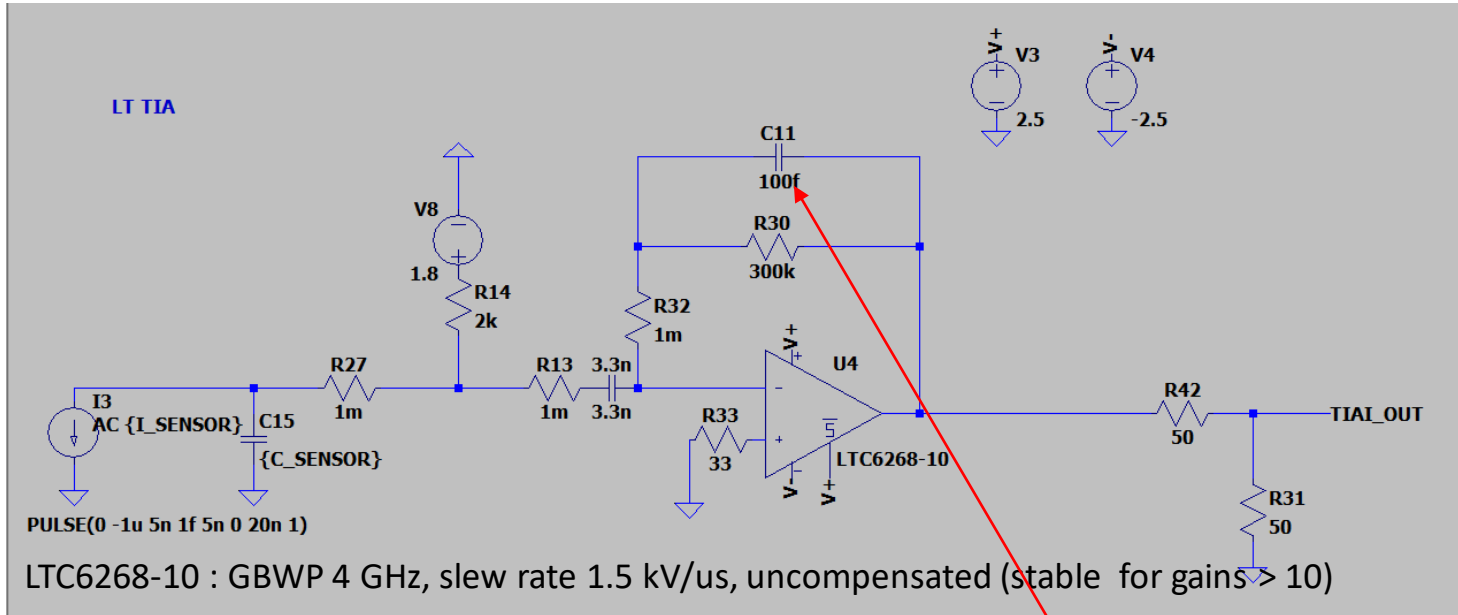
I-V curves measured on different samples  
(bonded on PCB)



I-V curves measured on different samples  
(Liverpool probe station)

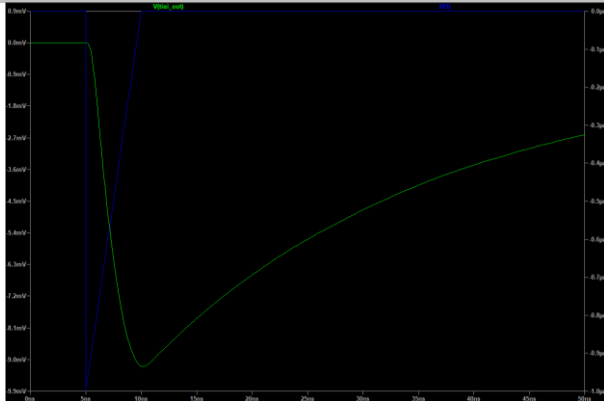


# Discrete front-end : opamp TIA



Front-end performance limited by parasitic caps

S/N with this discrete front-end does not allow good timing measurement (and this design was not intended for timing)



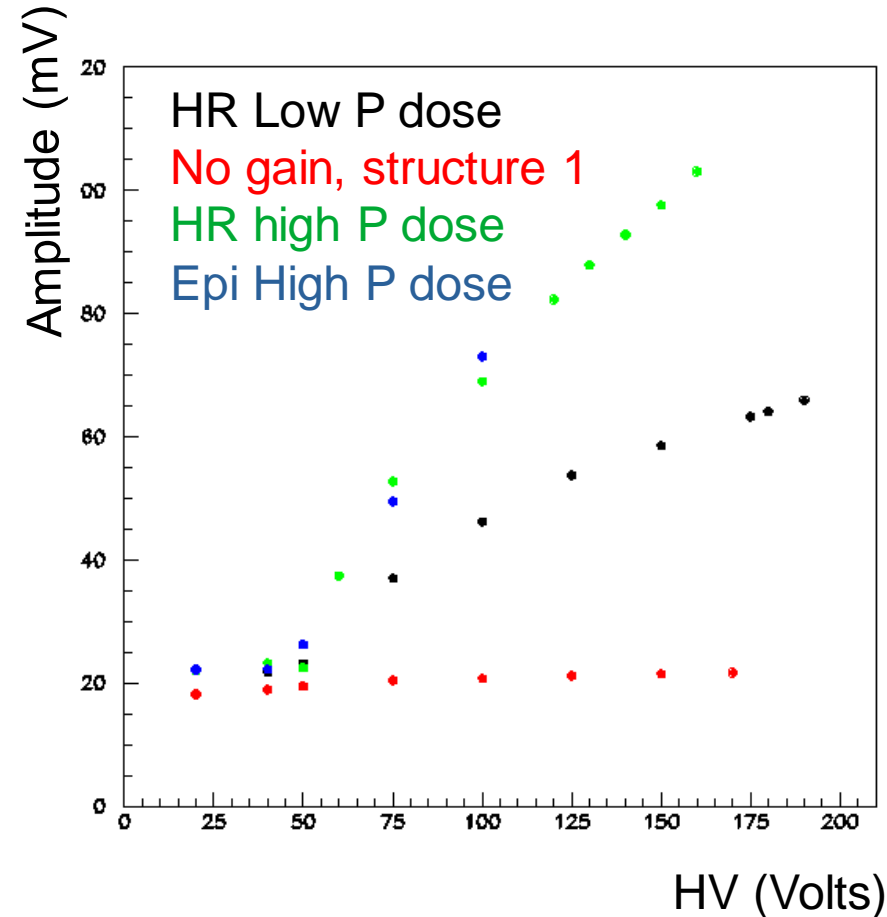
TIA architecture, AC coupled.

Relatively long risetime (7 ns), noise about 2 mV rms

Parasitic capacitance (C11) in feedback loop is critical. Value given here is a guesstimate deduced from practical observations.

Output amplitude for a MIP (no gain) about 8 mV, no need for external amplification

# IR LED amplitude measurements



- The clear amplitude vs HV behaviour difference between no gain and gain structure unambiguously proves there is charge multiplication occurring
- Signal amplitude high for high P dose chips than for low P dose, as anticipated from TCAD
- Charge multiplication starts earlier than predicted by TCAD, around 50 V instead of 100 V
- Epi high P dose gives interestingly high signals, given the low thickness ( $28\ \mu$ ) of collecting diode
- Very large voltage range over which gain is present

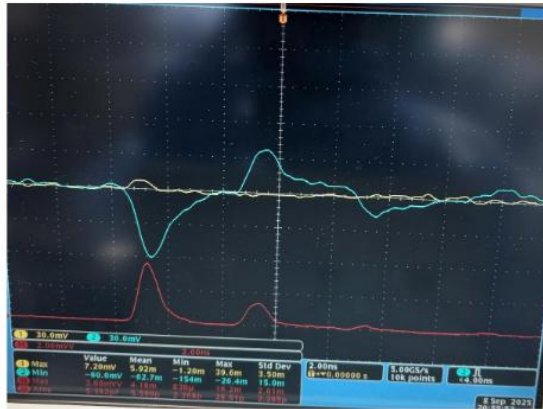
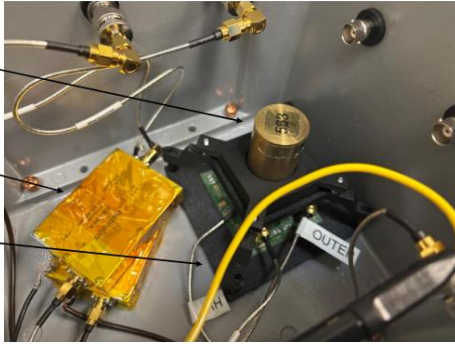
# 90Sr signals are visible even without FE

SR 90 Beta Source

Amplifiers connected to Left and Right Diodes, the to scope.

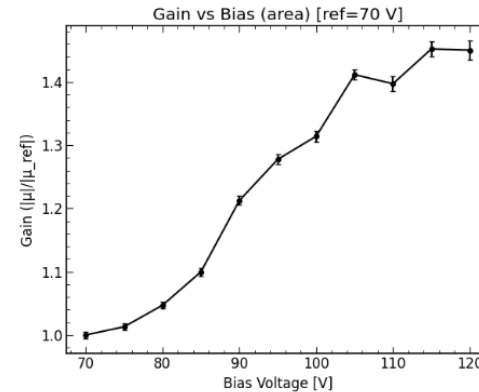
HV supply – connected to TopBias

DummyDiodes grounded, all other connections floating



- Diode under test
- Diode signal squared

## Epitaxial Wafer: Structure 2



• Not true 'gain' plotted, since no signal detected on structure 1 (reference)

• factor of 1.4 gain at 120V, compared to 70V

• Expected to be  $\approx 1.3$  if only caused by increase in depletion region.



# $^{90}\text{Sr}$ measurements

$^{90}\text{Sr}$  spectra (in coincidence with PMT below DUT) obtained on gain layer diodes from HR high P dose, HR low P dose, and epi high P dose. Epi low P dose still to be tested.

Peak not measurable on the version **wo gain** (due to S/N of external FE); only the **tail** of Landau visible

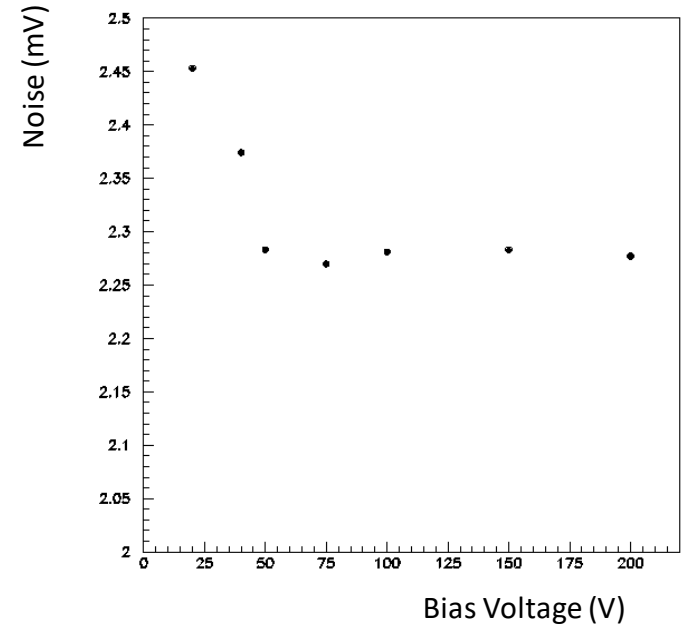
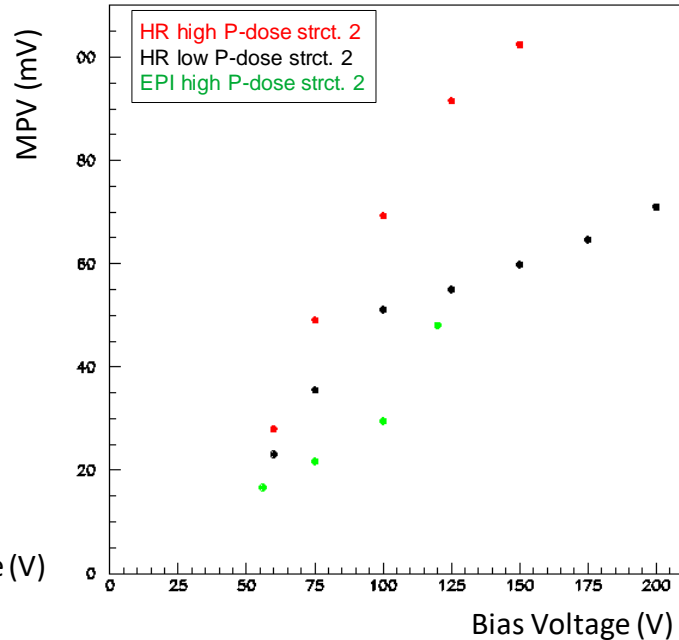
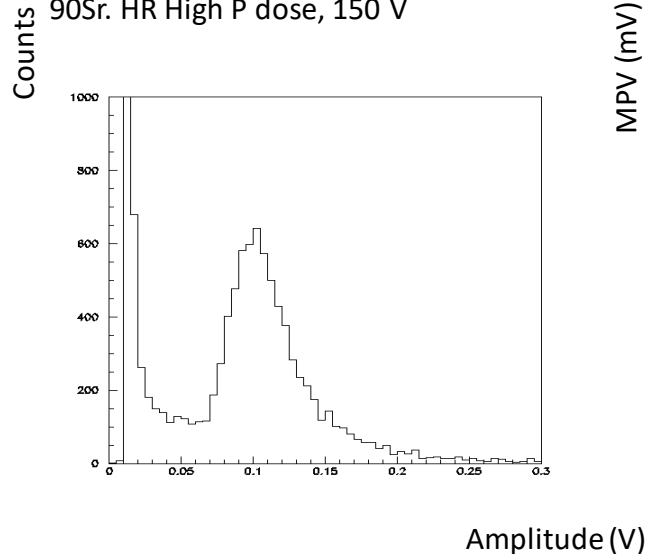
High P-dose gives higher gain and lower BV as expected from TCAD simulations

Very preliminary estimated gains using  $^{90}\text{Sr}$  source is about  $\approx 6$  for the low P-dose and  $\approx 10$  for the high P-dose

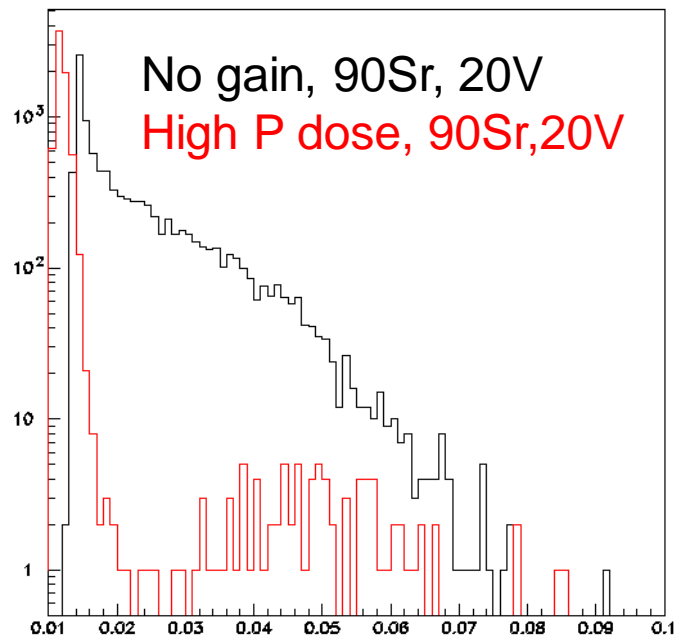
Capacitance variation visible (through noise measurement) below multiplication threshold

Typical Landau distribution obtained with

$^{90}\text{Sr}$ . HR High P dose, 150 V

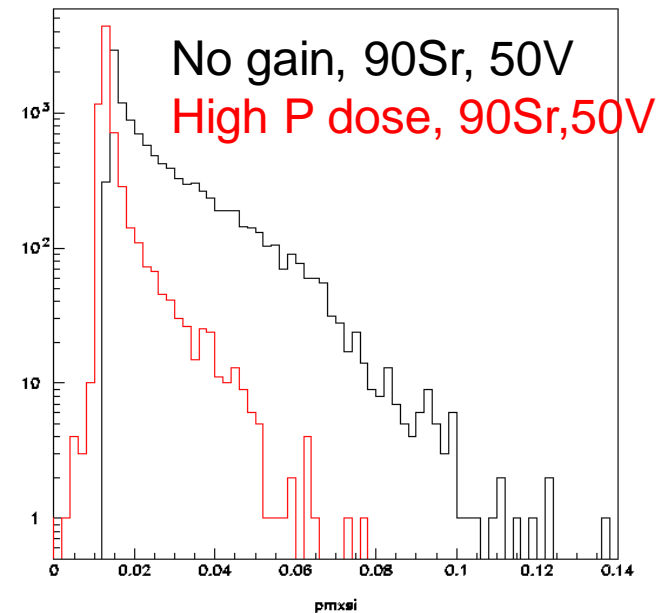


# Comparison of $^{90}\text{Sr}$ signals for amplified and non amplified structures below 50 V



Amplitude (V)

Response of a non amplified diode and an amplified diode are very different. Threshold effect due to gain layer ?



Amplitude (V)

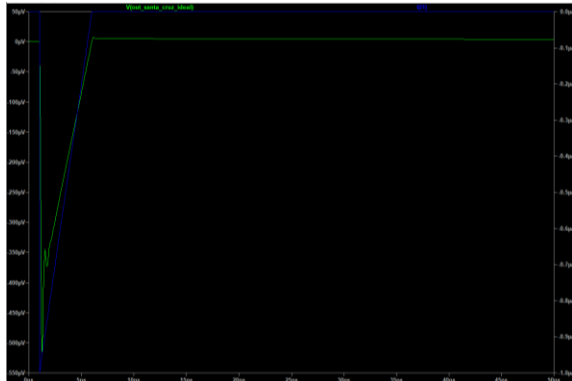
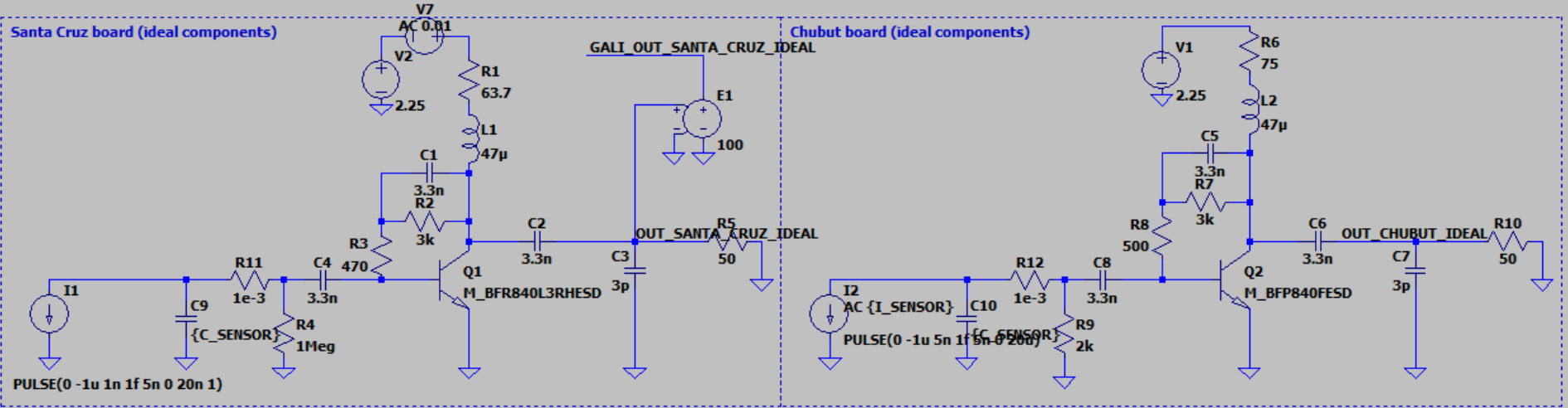
# Conclusions and prospects

- Test structures produced with LF15A process clearly show charge multiplication above 50 V
- Epi wafer gives particularly interesting results
- Measurements just started, have still to test structures 3,4,5,6. Structure 5 has systematically BV higher than others → particularly interesting
- Need to revisit TCAD simulation to optimize further gain layer
- Plan to submit a MiniCactus V2 with GL chip (with integrated FE, suitable for timing) and improved test structures (higher BV) together with Radpix for LHCb

# Backup

# RF FE design

.noise V(GALI\_OUT\_SANTA\_CRUZ\_IDEAL) I1 dec 100 1meg 11g



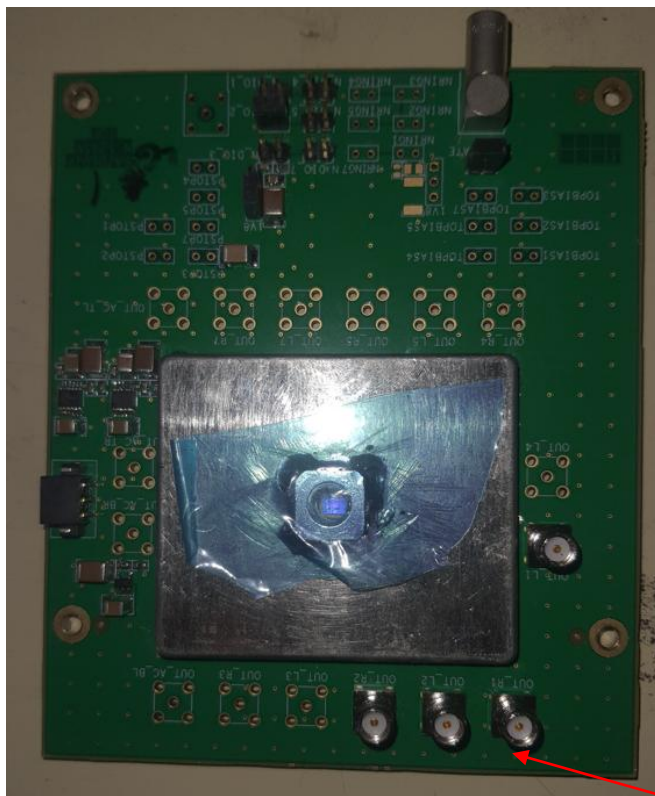
- CE BJT architecture, with SiGe heterojunction NPN RF transistor
- Copy/paste from Santa Cruz LGAD/Chubut test board (M. Senger, Zürich)
- Elaborate power rail filtering (not visible here)
- Very short risetime (800 ps), low noise (few hundreds of uV)
- Output amplitude very small (500 uV for a MIP), needs external voltage
- amplifier (Gali 52, x10)

# Test board design

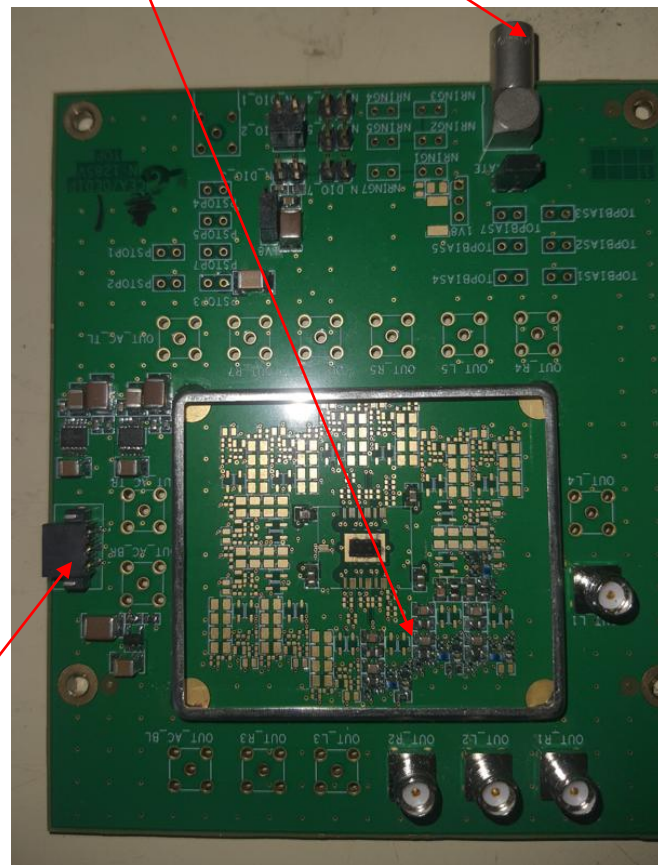
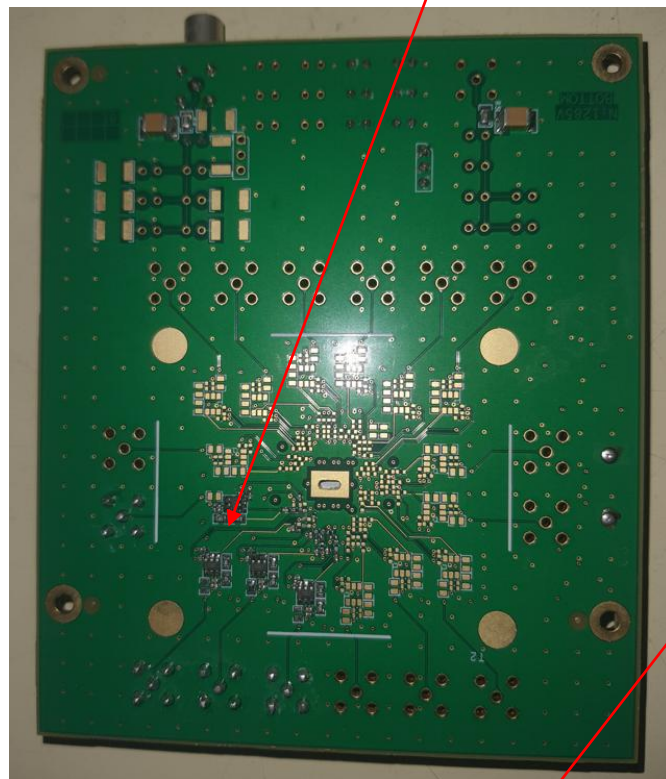
LT TIA (bottom)

RF FE (top)

HV (LEMO)



SMA Analog outputs

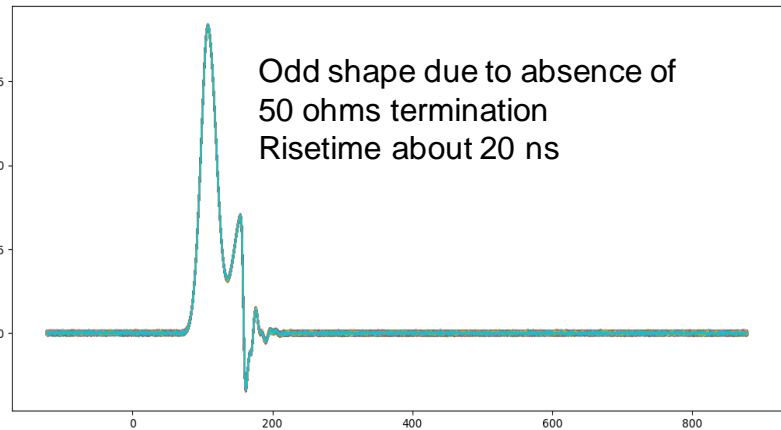


LV (+5/-5), same connector as MiniCactus

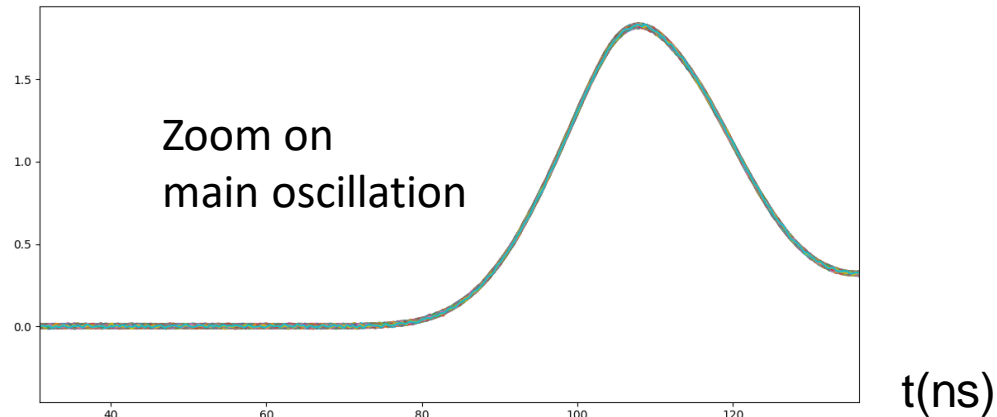
120 mm x 100 mm. Mounting compatible with MiniCactusV2 test frame,  
Same chip position and same mounting holes positions → can potentially be used in testbeam

# LED signals : injection with 940 nm IR diode

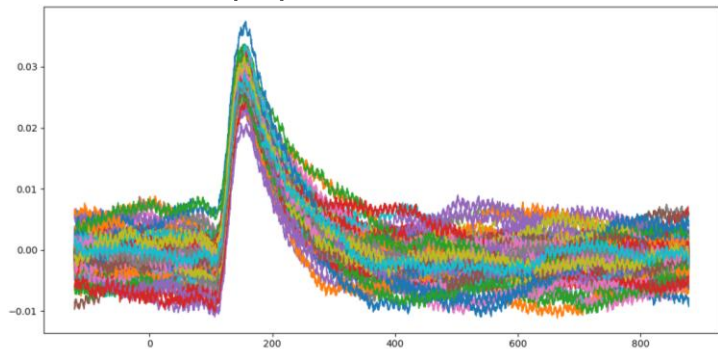
V<sub>gene</sub> (V)



V<sub>gene</sub> (V)

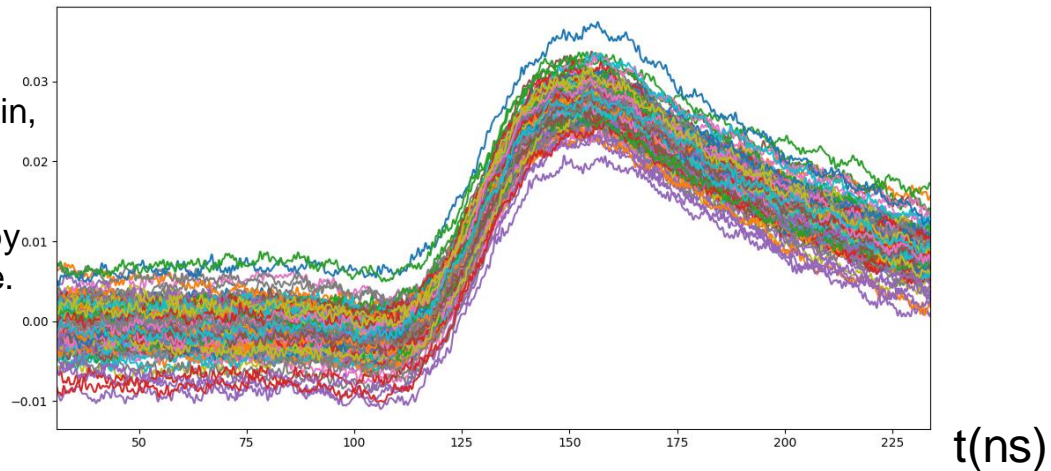


V<sub>out</sub> (V)



Structure 1, no gain,  
100V, HR wafer  
RT about 20 ns,  
likely dominated by  
AWG/Led risetime.

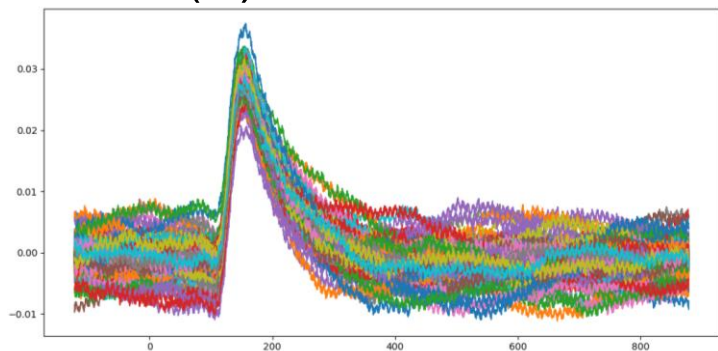
t(ns)





# LED signals : structure 1 (no gain) vs structure 2

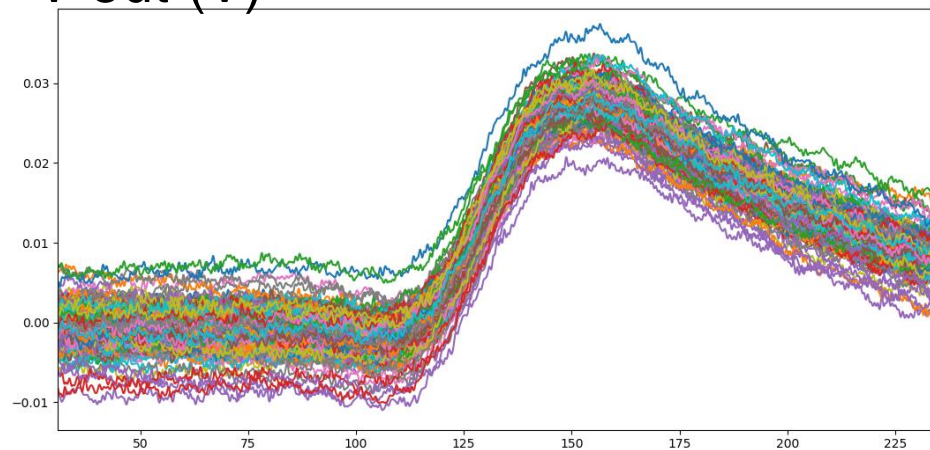
V out (V)



Structure 1, no gain,  
100V, HR wafer  
RT about 20 ns,  
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AWG/Led risetime.

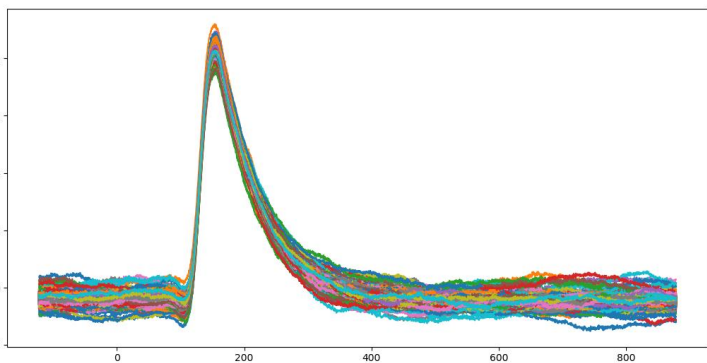
TIA LT FE

V out (V)



V out (V)

t(ns)

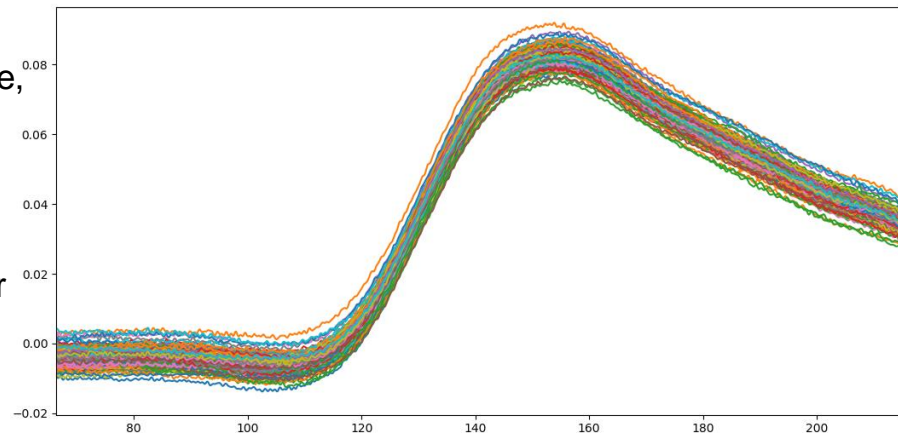


Structure 2, with gain  
layer, 100V, low P dose,  
HR wafer

Signal shape similar  
to no gain signals,  
amplitude much higher  
(80 mV vs 30 mV).  
Risetime about 20 ns

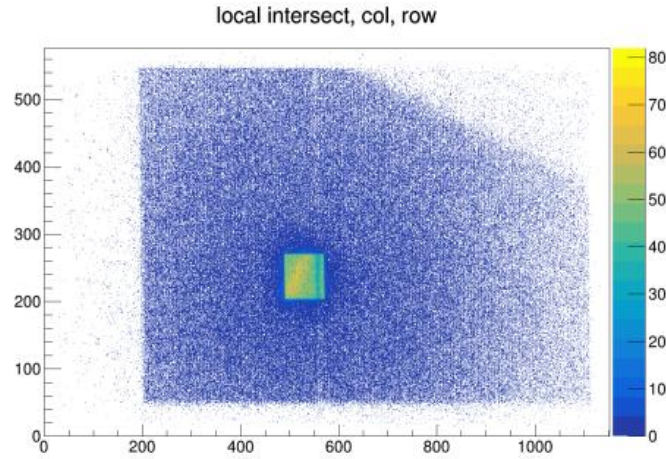
TIA LT FE

V out (V)

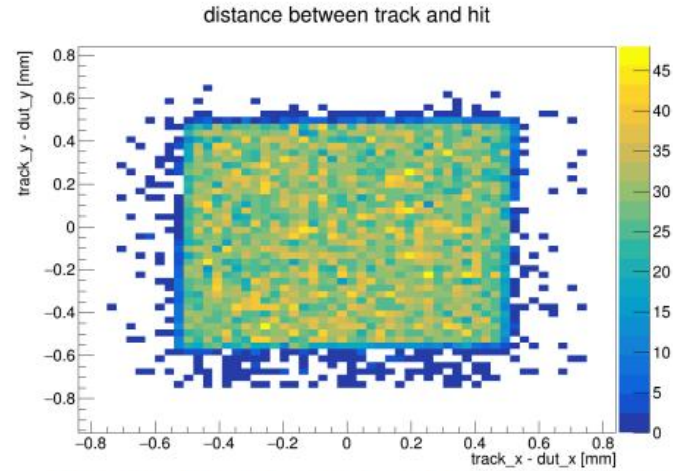


t(ns)

t(ns)



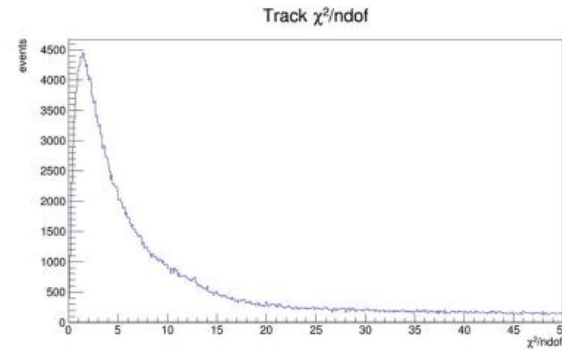
MIMOSA reference plane showing the ROI selected on the CROC, about  $1.1 \times 1.2 \text{ mm}^2$



Distance from the tracks with hits on the DUT from the center of the DUT pad



- We assumed a hit if the analog output signal of the DUT was higher than 0.06 V
- Events for the efficiency calculated where selected for:
  - Single track/event
  - Event detected on at least 4 planes
  - Events intercepting the DUT



Track  $\chi^2/\text{ndof}$

*Preliminary – Ongoing analysis*